



**Entrance**

## Sample Preparation Area



**HALT System -**  
(Highly Accelerated Lifetime Testing)



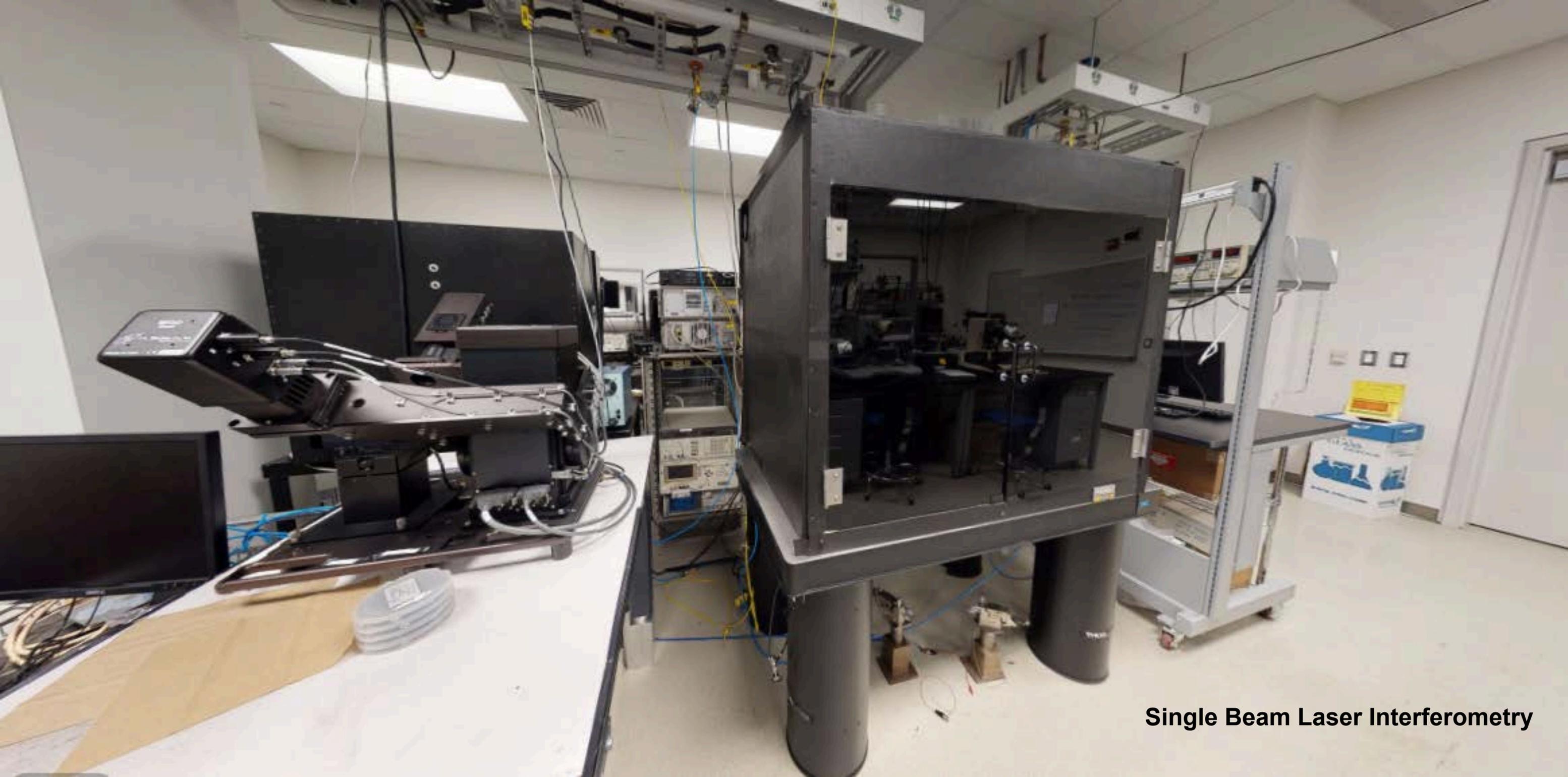
# Wire Bonding Stations

BE YOU LEAVE -  
you tidy up & disinfect  
move everything you brought  
questions/concerns:  
Sarah: (844) 460-330  
Paul: (824) 777-5013





**Ellipsometer** -  
For measuring the optical  
properties and thickness of films.



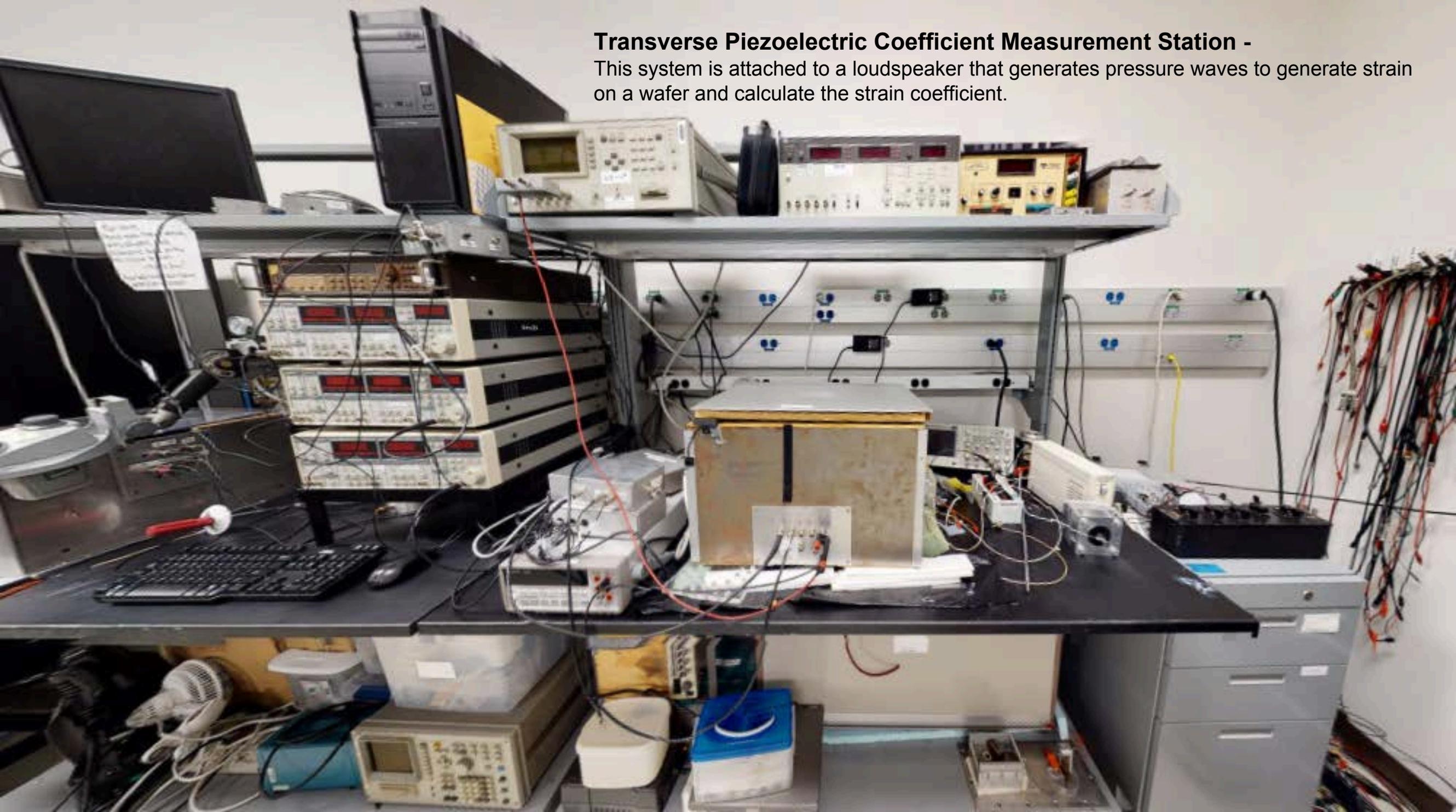
**Single Beam Laser Interferometry**



Area for new probe station

## Transverse Piezoelectric Coefficient Measurement Station -

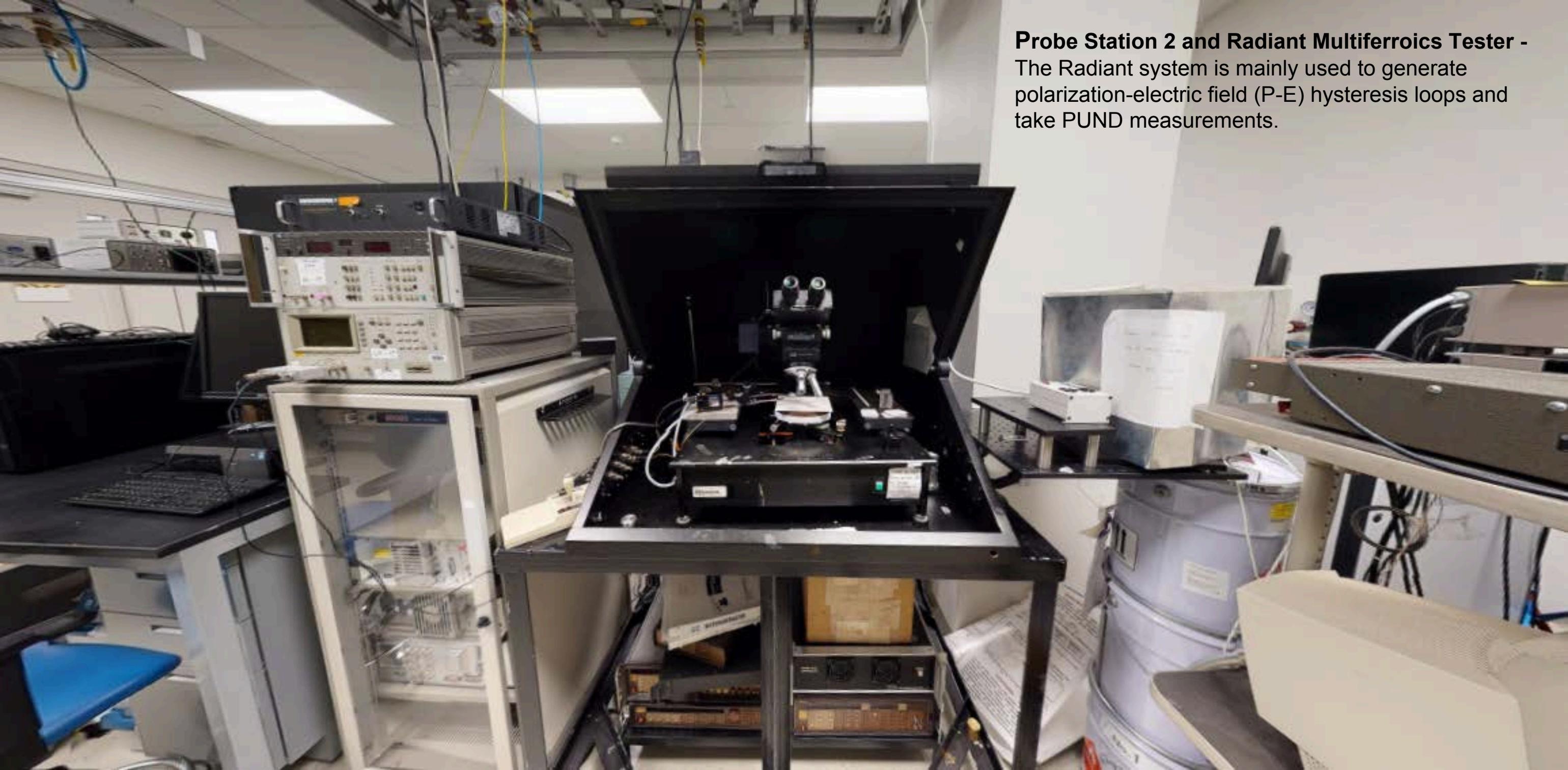
This system is attached to a loudspeaker that generates pressure waves to generate strain on a wafer and calculate the strain coefficient.



**Double-Beam Laser Interferometry Station -**  
Used to measure piezoelectric coefficients such as the  $d_{33}$  and testing hysteresis with S-E butterfly loops.



**Probe Station 2 and Radiant Multiferroics Tester -**  
The Radiant system is mainly used to generate polarization-electric field (P-E) hysteresis loops and take PUND measurements.





**Probe Station 1**

**C-D and I-V Measurement Stations -**

This equipment is used to gather a range of information including capacitance, impedance, and loss up to 1 MHz, leakage current density, and more.

